IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Cabral, Jr. et al.

Serial No.: 09/902,483

Group Art Unit: 2813

J65

Filing Date: July 11, 2001

Examiner: Unknown

11-23-01

For:

SELF-ALIGNED SILICIDE (SALICIDE) PROCESS FOR LOW RESISTIVITY CONTACTS TO THIN FILM SILICON-ON-INSULATOR AND BULK MOSFETS AND FOR SHALLOW JUNCTIONS

Assistant Commissioner of Patents Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

Under the provisions of 37 CFR §1.97 through §1.99 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following documents listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. Copies of the listed documents are provided herewith for the convenience of the Examiner.

This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application

Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's Deposit Account No. 50-0510.

Respectfully submitted,

Sean M. McGinn

Registration No. 34,386

Date: September 19, 2001
McGinn & Gibb, PLLC
Intellectual Property Law
8321 Old Courthouse Road, Suite 200
Vienna, Virginia 22182-3817
(703) 761-4100
Customer No. 21254